

Figure 1

200

220

210

Processing Tool	P1 50 / 5	P2 25 / 3	P3 25 / 2	
Metrology Tool	M1 55 / 6	M2 45 / 4		
Wafer Profile	Dished 50 / 1	Domed 25 / 8	Flat 25 / 1	
Deposition Time	0-50 0 / 0	50-100 25 / 3	100-150 55 / 5	150-200 20 / 2

Figure 2

3 / 3

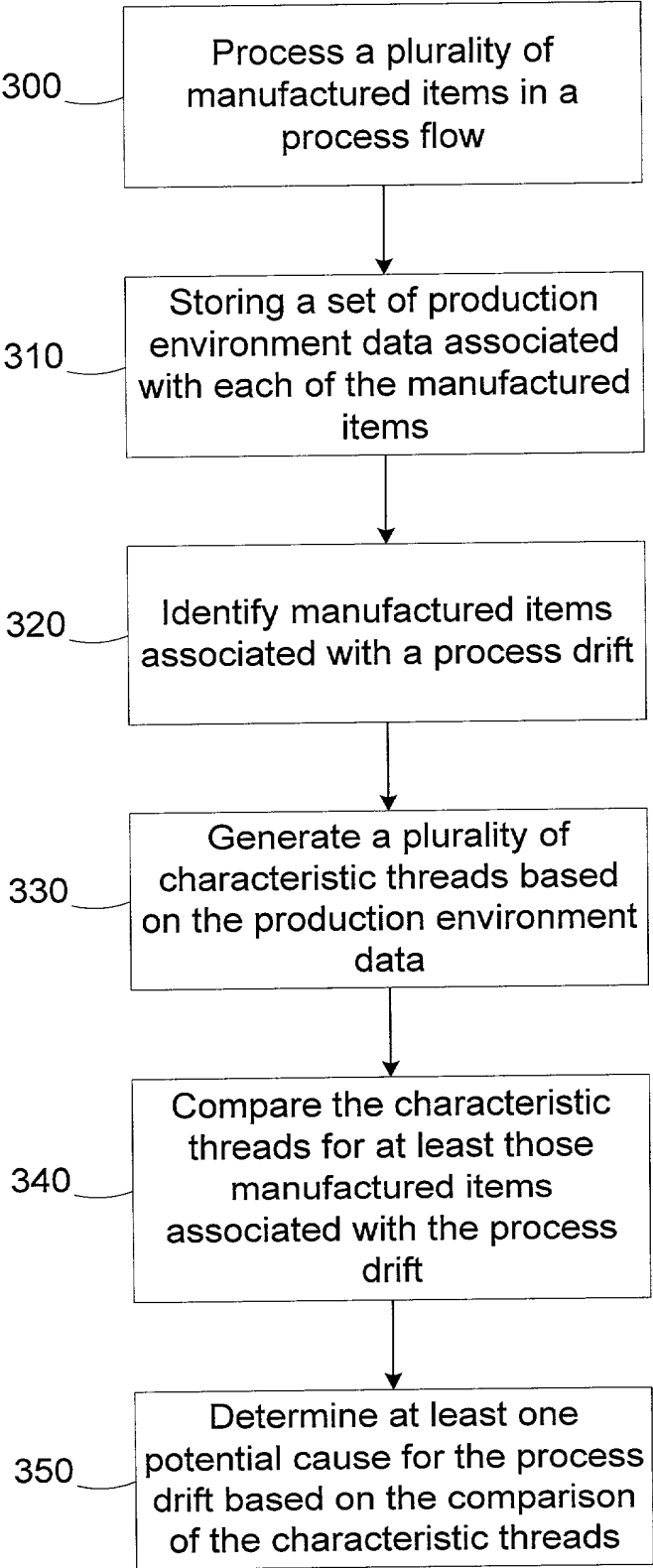


Figure 3